

## Japan I&C Committee Meeting Summary and Minutes

Japan Standards Spring 2013 Meetings  
April 10, 2013, 1:30 p.m. - 5:00 p.m.  
JPR Conference Room 1, SEMI Japan, Tokyo

### Next Committee Meeting

June 19, 2013, 1:30 p.m. - 5:00 p.m. Japan Standard Time  
Japan Standards Summer 2013 Meeting, Tokyo, Japan

### Table 1 Meeting Attendees

**Co-Chairs:** Takayuki Nishimura (Dainippon Screen MFG.), Mitsuhiro Matsuda (Hitachi Kokusai Electric)

**SEMI Staff:** Chie Yanagisawa

**Attendee:** 13 + SEMI: 1

| <i>Company</i>            | <i>Last</i> | <i>First</i> | <i>Company</i>   | <i>Last</i> | <i>First</i> |
|---------------------------|-------------|--------------|------------------|-------------|--------------|
| Algo System               | Ogihara     | Hideaki      | Murata Machinery | Kondo       | Hiroshi      |
| Cannon Anelva             | Sato        | Mitsugu      | Tokyo Electron   | Asakawa     | Terry        |
| Dainippon Screen MFG.     | Nishimura   | Takayuki     | Tokyo Electron   | Mochizuki   | Tadashi      |
| Dainippon Screen MFG.     | Takasaki    | Yoshihisa    | Tokyo Electron   | Murata      | Naoko        |
| F.B Consult               | Somei       | Tadashi      | Tokyo Electron   | Sakamoto    | Mitch        |
| Hitachi High Technologies | Toyoshima   | Yuko         | Tokyo Seimitsu   | Sasaki      | Mie          |
| Hitachi Kokusai Electric  | Matsuda     | Mitsuhiro    | SEMI Japan       | Yanagisawa  | Chie         |

### Table 2 Leadership Changes

| <i>Group</i> | <i>Previous Leader</i> | <i>New Leader</i> |
|--------------|------------------------|-------------------|
| None         |                        |                   |

### Table 3 Ballot Results (or move to Section 4, Ballot Review)

**Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

**Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting.

| <i>Document #</i> | <i>Document Title</i>   | <i>Committee Action</i>                                      |
|-------------------|---|--|
| 5422              | New Standard: Guide for Equipment Information System Security   | <b>Failed</b> and was returned to the Task Force for rework. |
| 5423A             | Line-item Revision to SEMI E40.1-0312 SECS-II Support for Processing Management Standard and SEMI E5-0712 SEMI Equipment Communications Standard 2 Message Content (SECS-II); Add mapping to PPID for RecID |  |
| Line Item 1       | Add mapping to PPID for RecID   | <b>Passed</b> as balloted                                    |
| Line Item 2       | Editorial Change of E5-0712   | Superclean   |

### Table 4 Authorized Ballots (or move to Section 7, New Business)

| <i>#</i> | <i>When</i> | <i>SC/TF/WG</i> | <i>Details</i> |
|----------|-------------|-----------------|----------------|
| None     |             |                 |                |

### Table 5 Authorized Activities (or move to Section 7, New Business)

| <i>#</i> | <i>Type</i> | <i>SC/TF/WG</i> | <i>Details</i> |
|----------|-------------|-----------------|----------------|
| None     |             |                 |                |

Note: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

**Table 6 New Action Items (or move to Section 8, Action Item Review)**

| <i>Item #</i> | <i>Assigned to</i> | <i>Details</i>  |
|---------------|--------------------|---|
| 1             | SEMI Staff         | To inactivate SNARF 5367  |
| 2             | Hideaki Ogihara    | To consider whether or not SEMI E98-0309 should be revised or reapproved    |
| 3             | Sensor Bus TF      | To consider whether or not SEMI E54.19-0308 should be revised or reapproved |

**Table 7 Previous Meeting Actions Items (or move to Section 8, Action item Review)**

| <i>Item #</i> | <i>Assigned to</i> | <i>Details</i>   |
|---------------|--------------------|--|
| 1             | Mitsuhiro Matsuda  | Report for the previous Action Item JICC120419-4: To collect comments about SNARF pre-distribution rule from all members of Japan Information & Control Committee<br>→Done. See Section 7.1. |
| 2             | SEMI Staff         | Report for the previous Action Item JICC121207-1: To ask SEMI Staff in Europe to provide the liaison report →Done.   |

## 1 Welcome, Reminders, and Introductions

Takayuki Nishimura (Dainippon Screen MFG.) called the meeting to order at 13:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment:** 01, Required Elements Reg\_20100302\_E+J

## 2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting. Naoko Murata (Tokyo Electron) pointed out there are some clerical errors in the Attendees' Names.

**Motion:** Approve the minutes of the previous meeting with the collection of the Attendees' Names.

**By / 2<sup>nd</sup>:** Mitsuhiro Matsuda (Hitachi Kokusai Electric) / Mitsugu Sato (Canon Anelva)

**Discussion:**None

**Vote:** 12:0

**Attachment:** 02, Japan ICC Minutes 121207 R0.6

## 3 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. Of note:

- Global SEMI Events
- Standards Meetings during SEMICON West
- Ballot Critical Dates
- Publication Update
- ISC A&R SC Summary February 2013
- Recent Regulations & Procedure Guide Revisions
- Contact Information

**Attachment:** 03, SEMI Staff Report 2013 April R1.0

## 4 Liaison Reports

### 4.1 North America I&C Committee

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the North America I&C Committee. Of note:

- Leadership
- Organization Chart
- Meeting Information
- Ballot Results

- Upcoming Ballots
- Task Force Reports
- Upcoming Meeting Schedule

**Attachment:** 04, NA I&C report April 2013

#### 4.2 *Europe Equipment Automation Committee*

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Europe Equipment Automation Committee. Of note:

- Leadership
- Committee Organization
- Meeting Information
- Activity highlights
- **Attachment:** 05, EA Liaison Report\_April 2013

#### 4.3 *Taiwan I&C Committee*

Chie Yanagisawa (SEMI Japan) reported that the message from SEMI Taiwan Staff there was no update for the Taiwan I&C Committee.

#### 4.4 *Korea I&C Committee*

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Korea I&C Committee. Of note:

- Leadership
- Organization Chart
- Meeting Information
- Major Updates
- Task Force Updates

**Attachment:** 06, KR\_I&C\_liaison\_20130401

## 5 **Ballot Review**

### 5.1 Document # 5422, New Standard: Guide for Equipment Information System Security

- Document **failed** technical review and was returned to the EISS task force for rework and rebalot. See attachment below for detail of ballot adjudication.

**Attachment:** 07, 5422 Ballot Review Result

5.2 Document # 5423A, Line-item Revision to SEMI E40.1-0312 SECS-II Support for Processing Management Standard and SEMI E5-0712 SEMI Equipment Communications Standard 2 Message Content (SECS-II); Add mapping to PPID for RecID

#### 5.2.1 Line Item 1: Add mapping to PPID for RecID

- Document passed technical review as balloted. See attachment below for detail of ballot adjudication.

**Attachment:** 08, 5423A Ballot Review Result

#### 5.2.2 Line Item 2: Editorial Change of E5-0712

- Superclean. See attachment below for detail of ballot adjudication.

**Attachment:** 08, 5423A Ballot Review Result

## 6 **Subcommittee & Task Force Reports**

### 6.1 AMHS Task Force

Hiroshi Kondo (Murata Machinery) reported that there was no update.

## 6.2 GEM 300 Task Force

Yoshihisa Takasaki (Dainippon Screen MFG.) reported for the GEM 300 Task Force. The report contained the task force decided to withdraw SNARF 5367 (Revision to E87, Load Port Transfer Error Indication), because it cannot solve the problem only in the condition of Load Port Transfer State of E87. The motion was made as below:

**Motion:** To withdraw SNARF 5367  
**By / 2<sup>nd</sup>:** Yoshihisa Takasaki (Dainippon Screen MFG.) / Tadashi Mochizuki (Tokyo Electron)  
**Discussion:** None  
**Vote:** 12:0

**Action Item:** SEMI Staff to inactivate SNARF 5367.

**Attachment:** 09, JA\_GEM300TF Report\_130410\_R1

## 6.3 Equipment Information System Security (EISS) Task Force

Mitch Sakamoto (Tokyo Electron) reported for the Equipment Information System Security Task Force. This report contained information on the following items.

- Report at NA Standards Spring 2013 Meetings
- Review of the reject to Ballot 5422

**Attachment:** 10, EISS\_TF\_2013-04-10+02

## 6.4 Sensor Bus Task Force

Hideaki Ogihara reported for the Sensor Bus Task Force. The task force plans to issue a letter ballot for the revision of SEMI E54.12 “Specification for Sensor/Actuator Network Communications for CC-Link” to add the latest SDM mapping.

## 6.5 Predictive Carrier Logistics (PCL) Task Force

Terry Asakawa (Tokyo Electron) reported for the Predictive Carrier Logistics Task Force.

**Attachment:** 11, PCL\_TF\_Report\_for\_I&CC\_2013\_0410\_R1.00

## 7 Old Business

7.1 Report for the previous Action Item JICC120419-4: To collect comments about SNARF pre-distribution rule from all members of Japan Information & Control Committee, assigned by Mitsuhiro Matsuda (Hitachi Kokusai Electric).

Mitsuhiro Matsuda (Hitachi Kokusai Electric) presented the paragraphs of SNARF proposal and SNARF preparation from the SEMI Standards Procedure Guide and proposed a SNARF pre-distribution rule in Japan Information and Control Committee.

In response, Japan Information and Control Committee decided to make a notice of the SNARF (before Japan Information and Control Committee review) to GCS members after an initial review is completed by the co-chairs of Japan Information and Control Committee when they receive a SNARF.

7.2 Report for the previous Action Item JICC121207-1: SEMI Staff in Japan asks SEMI Staff in Europe to provide the liaison report. → Done

## 8 New Business

8.1 5-year-review documents; SEMI E98 and SEMI E54.19

8.1.1 SEMI E98

**Action Item:** Hideaki Ogihara (Algo System) to go through SEMI E98 for 5-year-review at first.

8.1.2 SEMI E54.19

**Action Item:** Sensor Bus TF to go through SEMI E54.19 for 5-year-review.

## 9 Action Item Review

### 9.1 Open Action Items

None.

### 9.2 New Action Items

**Action Item 1:** SEMI Staff to inactivate SNARF 5367.

**Action Item 2:** Hideaki Ogihara (Algo System) to go through SEMI E98 for 5-year-review at first.

**Action Item 3:** Sensor Bus TF to go through SEMI E54.19 for 5-year-review.

## 10 Next Meeting and Adjournment

The next meeting of the Japan I&C committee is scheduled for Wednesday, June 19, 2013 at Japan Standards Summer Meetings 2013 in SEMI Japan Office, Tokyo, Japan.

Respectfully submitted by:

Chie Yanagisawa  
Senior Standard Coordinator  
SEMI Japan  
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Email: cyanagisawa@semi.org

Minutes approved by:

|  |                |
|--|----------------|
| Takayuki Nishimura (Dainippon Screen MFG.), Co-chair   | April 25, 2013 |
| Mitsuhiro Matsuda (Hitachi Kokusai Electric), Co-chair | April 25, 2013 |

**Table 8 Index of Available Attachments #1**

| #  | Title                              | #  | Title                                  |
|----|------------------------------------|----|--|
| 01 | Required Elements Reg_20100302_E+J | 07 | 5422 Ballot Review Result              |
| 02 | Japan ICC Minutes 121207 R0.7      | 08 | 5423A Ballot Review Result             |
| 03 | SEMI Staff Report 2013 April R1.0  | 09 | JA_GEM300TF Report_121207_R1           |
| 04 | NA I&C report April 2013           | 10 | EISS_TF_2012-12_06_Report              |
| 05 | EA Liaison Report_April 2013       | 11 | PCL_TF_Report_for_I&CC_2013_0410_R1.00 |
| 06 | KR_I&C_liaison_20130401            |    |  |

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.